## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: IRINO, Kiyoshi

Serial No.: 09/428,052

Filed: **October 27, 1999** 

Group Art Unit: 2815

Examiner: DIAZ, Jose R.

Conformation No.: 4139

Date: December 8, 2003

METHOD OF FABRICATING A SEMICONDUCTOR DEVICE CONTAINING For: NITROGEN IN A GATE OXIDE FILM

## **PETITION FOR EXTENSION OF TIME**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Office Action dated August 7, 2003, for one month from November 7, 2003 to December 8, 2003 (December 7, 2003 was a Sunday).

Attached please find a check in the amount of \$110.00 to cover the cost of the extension. In the event that any additional fees are due in connection with this paper, please charge our Deposit Account No. 50-2866. This paper is filed in triplicate.

Respectfully submitted,

WESTERMAN, HATTORI, DANIELS & ADRIAN, LEP

JOHN KONG Stephen G. Adrian Reg. No. 32,878

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SGA/arf

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